

Day : Thursday

Date: 2/8/2007

Time: 14:26:30

PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = BARGERON

First Name = CORY

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09952398 	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	BARGERON, CORY
09952649	6913796 	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BARGERON, CORY

Inventor Search Completed: No Records to Display.

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = MARGOLIS

First Name = ARI

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09952398	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	MARGOLIS, ARI
10065861	Not Issued	80	11/26/2002	Drying process for low-k dielectric films	MARGOLIS, ARI

Inventor Search Completed: No Records to Display.

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MARGOLIS

First Name

ARI

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	L #	Hit s	Search Text	DBs	Time Stamp
1	L1	2	("6596404").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2007/02/08 16:28
2	L2	20	(("6759098") or ("6913796") or ("7011868") or ("6558755") or ("6759133") or ("5707681") or ("5866197") or ("5906859") or ("6022625") or ("6210749")).PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2007/02/08 17:04
3	L3	5	↓ L2 and (UV ultraviolet ultra adj violet actinic irradiat\$5 radiat\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2007/02/08 17:16
4	L4	2	("5059448").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	2007/02/08 17:15
5	L5	2	↓ L4 and (UV ultraviolet ultra adj violet actinic irradiat\$5 radiat\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	2007/02/08 17:16

From Inventor Name Search
10/623, 712

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PALM INTRANET**Inventor Information for 10/623712**

Inventor Name	City	State/Country
WALDFRIED, CARLO	FALLS CHURCH	VIRGINIA
HAN, QINGYUAN	COLUMBIA	MARYLAND
ESCORCIA, ORLANDO	FALLS CHURCH	VIRGINIA
BERRY, IVAN L. III	ELLICOTT CITY	MARYLAND
BREMMER, JEFF	MIDLAND	MICHIGAN
DEMBOWSKI, PHIL	MIDLAND	MICHIGAN

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = WALDFRIED

First Name = CARLO

HAVE

parent

post-trunk

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09114999	6184523	150	07/14/1998 <i>Nu</i>	HIGH RESOLUTION CHARGED PARTICLE-ENERGY DETECTING, MULTIPLE SEQUENTIAL STAGE, COMPACT, SMALL DIAMETER, RETRACTABLE CYLINDRICAL MIRROR ANALYZER SYSTEM, AND METHOD OF USE	WALDFRIED, CARLO
09543373	Not Issued	161	04/02/2000	Post etch photoresist and residue removal process	WALDFRIED, CARLO
09681332	6558755	150	03/19/2001	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	WALDFRIED, CARLO
09855177	6630406	150	05/14/2001	PLASMA ASHING PROCESS	WALDFRIED, CARLO
09864003	6834656	150	05/23/2001	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	WALDFRIED, CARLO
09906276	6759098	150	07/16/2001	PLASMA CURING OF MSQ BASED POROUS LOW-K FILM MATERIALS	WALDFRIED, CARLO
<i>new prep pub</i> 09911682	6548416	150	07/24/2001	PLASMA ASHING PROCESS	WALDFRIED, CARLO
09952398	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	WALDFRIED, CARLO
<i>new prep pub</i> 09952649	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
<i>new prep pub</i> 10065861	Not Issued	80	11/26/2002 <i>?</i>	Drying process for low-k dielectric films	WALDFRIED, CARLO
10248707	7078161	150	02/11/2003	PLASMA ASHING PROCESS	WALDFRIED,

				FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	CARLO
<u>10249962</u>	Not Issued	71	05/22/2003	PLASMA APPARATUS, GAS DISTRIBUTION ASSEMBLY FOR A PLASMA APPARATUS AND PROCESSES THEREWITH	WALDFRIED, CARLO
<u>10346560</u>	Not Issued	168	01/17/2003	Fluorine-free plasma curing process for porous low-k materials	WALDFRIED, CARLO
<u>10384141</u>	Not Issued	161	03/07/2003	Plasma curing process for porous silica thin film	WALDFRIED, CARLO
<u>10623712</u>	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	WALDFRIED, CARLO
<u>10623729</u>	6756085	150	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	WALDFRIED, CARLO
<u>10627894</u>	7011868	150	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
<u>10638570</u>	6951823	150	08/11/2003	PLASMA ASHING PROCESS	WALDFRIED, CARLO
<u>10987276</u>	Not Issued	41	11/12/2004 next	Ultraviolet assisted pore sealing of porous low k dielectric films	WALDFRIED, CARLO
<u>11146742</u>	Not Issued	30	06/07/2005	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	WALDFRIED, CARLO
<u>11146744</u>	Not Issued	25	06/07/2005	Ultraviolet curing process for spin-on dielectric materials used in pre-metal and/or shallow trench isolation applications	WALDFRIED, CARLO
<u>11155525</u>	Not Issued	25 Chm 32	06/17/2005 July 8	Apparatus and process for treating dielectric materials	WALDFRIED, CARLO
<u>11446052</u>	Not Issued	25	06/02/2006	Ultraviolet curing process for low k dielectric films	WALDFRIED, CARLO
<u>60577679</u>	Not Issued	159	06/07/2004	Ultraviolet curing process for spin-on dielectric materials used in pre-metal and/or shallow trench isolation applications	WALDFRIED, CARLO



<u>60577726</u>	Not Issued	159	06/07/2004	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	WALDFRIED, CARLO
<u>60581185</u>	Not Issued	159	06/18/2004	Apparatus for curing and/or removing porogens from low k and/or premetal dielectric materials	WALDFRIED, CARLO

Inventor Search Completed: No Records to Display.

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = HAN

First Name = QINGYUAN

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09368553	6281135	150	08/05/1999 X	OXYGEN FREE PLASMA STRIPPING PROCESS	HAN, QINGYUAN
09528835	6576300	150	03/20/2000	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	HAN, QINGYUAN
09531885	6406836	150	03/21/2000 X	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	HAN, QINGYUAN
09681332	6558755	150	03/19/2001 7	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	HAN, QINGYUAN
09855177	6630406	150	05/14/2001 X	PLASMA ASHING PROCESS	HAN, QINGYUAN
09906276	6759098	150	07/16/2001	PLASMA CURING OF MSQ-BASED POROUS LOW-K FILM MATERIALS	HAN, QINGYUAN
09911682	6548416	150	07/24/2001 X	PLASMA ASHING PROCESS	HAN, QINGYUAN
09952398	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	HAN, QINGYUAN
09952649	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	HAN, QINGYUAN
10248707	7078161	150	02/11/2003 X	PLASMA ASHING PROCESS FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	HAN, QINGYUAN
10346560	Not Issued	168	01/17/2003	Fluorine-free plasma curing process for porous low-k materials	HAN, QINGYUAN
10384141	Not	161	03/07/2003	Plasma curing process for porous	HAN, QINGYUAN

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	Issued			silica thin film	
10413034	6759133	150	04/14/2003 ?	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	HAN, QINGYUAN
10623712	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	HAN, QINGYUAN
10623729	6756085	150	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	HAN, QINGYUAN
10627894	7011868	150	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	HAN, QINGYUAN
10638570	6951823	150	08/11/2003 P	PLASMA ASHING PROCESS	HAN, QINGYUAN
11146742	Not Issued	30	06/07/2005	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	HAN, QINGYUAN
60125616	Not Issued	159	03/22/1999	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	HAN, QINGYUAN
60577726	Not Issued	159	06/07/2004	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	HAN, QINGYUAN

Inventor Search Completed: No Records to Display.

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Last Name

HAN

First Name

QINGYUAN

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = ESCORCIA

First Name = ORLANDO

Application#	Patent#	Status	Date Filed	Title	Inventor Name
09855177	6630406	150	05/14/2001	PLASMA ASHING PROCESS	ESCORCIA, ORLANDO
09864003	6834656	150	05/23/2001	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	ESCORCIA, ORLANDO
09906276	6759098	150	07/16/2001	PLASMA CURING OF MSQ-BASED POROUS LOW-K FILM MATERIALS	ESCORCIA, ORLANDO
09952398	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	ESCORCIA, ORLANDO
09952649	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
10065861	Not Issued	80	11/26/2002	Drying process for low-k dielectric films	ESCORCIA, ORLANDO
10248707	7078161	150	02/11/2003	PLASMA ASHING PROCESS FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	ESCORCIA, ORLANDO
10346560	Not Issued	168	01/17/2003	Fluorine-free plasma curing process for porous low-k materials	ESCORCIA, ORLANDO
10623712	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	ESCORCIA, ORLANDO
10623729	6756085	150	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	ESCORCIA, ORLANDO
10627894	7011868	150	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO

<u>10638570</u>	6951823	150	08/11/2003	PLASMA ASHING PROCESS	ESCORCIA, ORLANDO
<u>10987276</u>	Not Issued	41	11/12/2004	Ultraviolet assisted pore sealing of porous low k dielectric films	ESCORCIA, ORLANDO
<u>11146742</u>	Not Issued	30	06/07/2005	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	ESCORCIA, ORLANDO
<u>11146744</u>	Not Issued	25	06/07/2005	Ultraviolet curing process for spin-on dielectric materials used in pre-metal and/or shallow trench isolation applications	ESCORCIA, ORLANDO
<u>11155525</u>	Not Issued	25	06/17/2005	Apparatus and process for treating dielectric materials	ESCORCIA, ORLANDO
<u>11446052</u>	Not Issued	25	06/02/2006	Ultraviolet curing process for low k dielectric films	ESCORCIA, ORLANDO
<u>60577679</u>	Not Issued	159	06/07/2004	Ultraviolet curing process for spin-on dielectric materials used in pre-metal and/or shallow trench isolation applications	ESCORCIA, ORLANDO
<u>60577726</u>	Not Issued	159	06/07/2004	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	ESCORCIA, ORLANDO
<u>60581185</u>	Not Issued	159	06/18/2004	Apparatus for curing and/or removing porogens from low k and/or premetal dielectric materials	ESCORCIA, ORLANDO
<u>60687576</u>	Not Issued	159	06/03/2005	Ultraviolet curing process for low k dielectric films	ESCORCIA, ORLANDO

Inventor Search Completed: No Records to Display.

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Day : Thursday

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = BERRY

First Name = IVAN

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>09528835</u> <i>HAN</i>	6576300	150	03/20/2000	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	BERRY III, IVAN LOUIS
<u>60036354</u>	Not Issued	159	01/23/1997	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHPUT SUB 0.1 UM LITHOGRAPHY	BERRY, III, IVAN L.
<u>09368553</u>	6281135	150	08/05/1999 <i>✓</i>	OXYGEN FREE PLASMA STRIPPING PROCESS	BERRY, IVAN
<u>09505695</u>	6734120	150	02/17/2000 <i>✓</i>	METHOD OF PHOTORESIST ASH RESIDUE REMOVAL	BERRY, IVAN
<u>09531885</u>	6406836	150	03/21/2000 <i>✓</i>	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	BERRY, IVAN
<u>09543373</u>	Not Issued	161	04/02/2000 <i>✓</i>	Post etch photoresist and residue removal process	BERRY, IVAN
<u>09732064</u>	6503366	150	12/07/2000 <i>✓</i>	CHEMICAL PLASMA CATHODE	BERRY, IVAN
<u>09855177</u>	6630406	150	05/14/2001 <i>✓</i>	PLASMA ASHING PROCESS	BERRY, IVAN
<u>09864003</u>	6834656	150	05/23/2001 <i>✓</i>	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	BERRY, IVAN
<u>09876318</u>	6638875	150	06/07/2001 <i>✓</i>	OXYGEN FREE PLASMA STRIPPING PROCESS	BERRY, IVAN
<u>09911682</u>	6548416	150	07/24/2001 <i>✓</i>	PLASMA ASHING PROCESS	BERRY, IVAN
<u>10000772</u>	6605484	150	11/30/2001 <i>✓</i>	PROCESS FOR OPTICALLY ERASING CHARGE BUILDUP DURING FABRICATION OF AN INTEGRATED CIRCUIT	BERRY, IVAN

10004523	6897615	150	11/01/2001	PLASMA PROCESS AND APPARATUS	BERRY, IVAN
10064219	6664737	150	06/21/2002	DIELECTRIC BARRIER DISCHARGE APPARATUS AND PROCESS FOR TREATING A SUBSTRATE	BERRY, IVAN
10065861	Not Issued	80	11/26/2002	Drying process for low-k dielectric films	BERRY, IVAN
10248779	6803319	150	02/18/2003	PROCESS FOR OPTICALLY ERASING CHARGE BUILDUP DURING FABRICATION OF AN INTEGRATED CIRCUIT	BERRY, IVAN
10336270	6673197	150	01/03/2003	CHEMICAL PLASMA CATHODE	BERRY, IVAN
10987276	Not Issued	41	11/12/2004	Ultraviolet assisted pore sealing of porous low k dielectric films	BERRY, IVAN
11146742	Not Issued	30	06/07/2005	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	BERRY, IVAN
11155525	Not Issued	25	06/17/2005	Apparatus and process for treating dielectric materials	BERRY, IVAN
60120866	Not Issued	159	02/19/1999	METHOD OF PHOTORESIST ASH RESIDUE REMOVAL	BERRY, IVAN
60125616	Not Issued	159	03/22/1999	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	BERRY, IVAN
60577726	Not Issued	159	06/07/2004	Ultraviolet assisted porogen removal and/or curing processes for forming porous low k dielectrics	BERRY, IVAN
60581185	Not Issued	159	06/18/2004	Apparatus for curing and/or removing porogens from low k and/or premetal dielectric materials	BERRY, IVAN
11295273	Not Issued	19	12/06/2005	Medium pressure plasma system for removal of surface layers without substrate loss	BERRY, IVAN I.
60633673	Not Issued	159	12/06/2004	Medium pressure plasma system for resist and organics removal with zero substrate loss	BERRY, IVAN I.
09681332	6558755	150	03/19/2001	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	BERRY, IVAN L.
09906276	6759098	150	07/16/2001	PLASMA CURING OF MSQ-	BERRY, IVAN L.

				BASED POROUS LOW-K FILM MATERIALS	
<u>09952398</u>	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	BERRY, IVAN L.
<u>09952649</u>	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BERRY, IVAN L.
<u>10346560</u>	Not Issued	168	01/17/2003	Fluorine-free plasma curing process for porous low-k materials	BERRY, IVAN L.
<u>10384141</u>	Not Issued	161	03/07/2003	Plasma curing process for porous silica thin film	BERRY, IVAN L.
<u>10623712</u>	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	BERRY, IVAN L.
<u>10623729</u>	6756085 <i>DAVE</i>	150	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	BERRY, IVAN L.
<u>10627894</u>	7011868 <i>V</i>	150	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BERRY, IVAN L.
<u>11633694</u>	Not Issued	25	12/04/2006 <i>X</i>	Use of ion induced luminescence (IIL) as feedback control for ion implantation	BERRY, IVAN L.
<u>06561747</u>	4631704	150	12/15/1983 <i>A</i>	METHODS AND DEVICES FOR CHARGED BEAM ACCESSIBLE DATA STORAGE	BERRY, IVAN L.
<u>09137504</u>	6300017	150	08/20/1998 <i>X</i>	STENCIL MASKS AND METHODS OF MANUFACTURING STENCIL MASKS	BERRY, IVAN L.
<u>60055052</u>	Not Issued	159	08/08/1997	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHPUT SUB 0.1 UM LITHOGRAPHY	BERRY, IVAN L.
<u>60072139</u>	Not Issued	159	01/22/1998	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHPUT SUB 0.1 UM LITHOGRAPHY	BERRY, IVAN L.
<u>10413034</u>	6759133 <i>✓</i>	150	04/14/2003	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	BERRY, IVAN LOUIS

Inventor Search Completed: No Records to Display.

Search Another: Inventor **Last Name**

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = BREMMER

First Name = JEFF

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>09952398</u>	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	BREMMER, JEFF
<u>09952649</u>	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BREMMER, JEFF
<u>10623712</u>	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	BREMMER, JEFF
<u>07973962</u>	5380479	150	11/09/1992	METHOD AND APPARATUS FOR PRODUCING <u>MULTILAYER PLASTIC ARTICLES</u>	BREMMER, JEFFREY N.
<u>08315374</u>	5628950	150	09/30/1994	METHOD AND APPARATUS FOR PRODUCING <u>MULTILAYER PLASTIC ARTICLES</u>	BREMMER, JEFFREY N.
<u>08698712</u>	Not Issued	161	08/16/1996	METHOD AND APPARATUS FOR PRODUCING <u>MULTILAYER PLASTIC ARTICLES</u>	BREMMER, JEFFREY N.
<u>08771627</u>	Not Issued	161	12/20/1996	METHOD OF PRODUCING LOW DIELECTRIC CERAMIC-LIKE MATERIALS	BREMMER, JEFFREY N.
<u>09130105</u>	Not Issued	168	08/17/1998	METHOD AND APPARATUS FOR PRODUCING <u>MULTILAYER PLASTIC ARTICLES</u>	BREMMER, JEFFREY N.
<u>08798405</u>	5707681	250	02/07/1997	METHOD OF PRODUCING COATINGS ON <u>ELECTRONIC SUBSTRATES</u>	BREMMER, JEFFREY NICHOLAS
<u>08870563</u>	5866197	150	06/06/1997	METHOD FOR PRODUCING <u>THICK CRACK-FREE COATINGS FROM HYDROGEN</u>	BREMMER, JEFFREY NICHOLAS

08870564	Not Issued	161	06/06/1997	SILSEQUOXANE RESIN THERMALLY STABLE DIELECTRIC COATINGS	BREMNER, JEFFREY NICHOLAS
08992832	Not Issued	163	12/17/1997	METHOD OF PRODUCING LOW DIELECTRIC CERAMIC-LIKE MATERIALS	BREMNER, JEFFREY NICHOLAS
09113347	5906859	250	07/10/1998	METHOD FOR PRODUCING LOW DIELECTRIC COATINGS FROM HYDROGEN SILSEQUOXANE RESIN	BREMNER, JEFFREY NICHOLAS
09128587	6022625	150	08/03/1998	METHOD FOR PRODUCING THICK CRACK-FREE COATINGS FROM HYDROGEN SILSESQUIOXANE RESIN	BREMNER, JEFFREY NICHOLAS
09516087	6210749	250	03/01/2000	Thermally stable dielectric coatings	BREMNER, JEFFREY NICHOLS

Inventor Search Completed: No Records to Display.

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Last Name

BREMNER

First Name

JEFF

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PALM INTRANET**Inventor Name Search Result**

Your Search was:

Last Name = DEMBOWSKI

First Name = PHIL

Application#	Patent#	Status	Date Filed	Title	Inventor Name
<u>09952649</u>	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	DEMBOWSKI, PHIL
<u>10623712</u>	Not Issued	30	07/21/2003	Low temperature UV pretreating of porous low-k materials	DEMBOWSKI, PHIL
<u>09980769</u>	6599814	150	02/19/2002	METHOD FOR REMOVAL OF SIC	DEMBOWSKI, PHILIP D.
<u>10359403</u>	6806501	150	02/05/2003	INTEGRATED CIRCUIT HAVING SIC LAYER	DEMBOWSKI, PHILIP D.
<u>10903914</u>	Not Issued	41	07/30/2004	METHOD FOR REMOVAL OF SIC	DEMBOWSKI, PHILIP D.

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Application#	Patent#	Status	Date Filed	Title	Inventor Name
09906276	6759098	150	07/16/2001	PLASMA CURING OF MSQ-BASED POROUS LOW-K FILM MATERIALS	ALBANO, RALPH
09952398	Not Issued	168	09/14/2001	Ultraviolet curing process for porous low-K materials	ALBANO, RALPH
09952649	6913796	150	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ALBANO, RALPH
10346560	Not Issued	168	01/17/2003	Fluorine-free plasma curing process for porous low-k materials	ALBANO, RALPH
10627894	7011868	150	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ALBANO, RALPH

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